

Mingwei Hong

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/9410851/publications.pdf>

Version: 2024-02-01

87
papers

2,984
citations

218677

26
h-index

168389

53
g-index

89
all docs

89
docs citations

89
times ranked

2016
citing authors

#	ARTICLE	IF	CITATIONS
1	Thickness-dependent topological phase transition and Rashba-like preformed topological surface states of $\text{In}_x\text{Sn}_{1-x}$ thin films on $\text{InSb}(001)$. <i>Physical Review B</i> , 2022, 105, .	3.2	4
2	Single-crystal epitaxial europium iron garnet films with strain-induced perpendicular magnetic anisotropy: Structural, strain, magnetic, and spin transport properties. <i>Physical Review Materials</i> , 2022, 6, .	2.4	7
3	<i>In situ</i> Y_2O_3 on $\text{p-In}_{0.53}\text{Ga}_{0.47}\text{As}$ Attainment of low interfacial trap density and thermal stability at high temperatures. <i>Applied Physics Letters</i> , 2021, 118, .	3.3	6
4	Topological insulator interfaced with ferromagnetic insulators: Bi_2Te_3 thin films on magnetite and iron garnets. <i>Physical Review Materials</i> , 2020, 4, .	2.4	19
5	Fundamental Understanding of Oxide Defects in HfO_2 and Y_2O_3 on $\text{GaAs}(001)$ with High Thermal Stability. , 2019, , .		1
6	Evidence for exchange Dirac gap in magnetotransport of topological insulator-magnetic insulator heterostructures. <i>Physical Review B</i> , 2019, 100, .	3.2	23
7	Topological insulator Bi_2Se_3 films on rare earth iron garnets and their high-quality interfaces. <i>Applied Physics Letters</i> , 2019, 114, .	3.3	14
8	BTI Characterization of MBE Si-Capped Ge Gate Stack and Defect Reduction via Forming Gas Annealing. , 2019, , .		3
9	Molecular beam epitaxy, atomic layer deposition, and multiple functions connected via ultra-high vacuum. <i>Journal of Crystal Growth</i> , 2019, 512, 223-229.	1.5	21
10	Strongly exchange-coupled and surface-state-modulated magnetization dynamics in $\text{Bi}_2\text{Se}_3/\text{yttrium iron garnet}$ heterostructures. <i>Nature Communications</i> , 2018, 9, 223.	12.8	63
11	High-quality single-crystal thulium iron garnet films with perpendicular magnetic anisotropy by off-axis sputtering. <i>AIP Advances</i> , 2018, 8, .	1.3	27
12	Exciton Localization of High-Quality $\text{ZnO}/\text{Mg}_{1-x}\text{Zn}_x\text{O}$ Multiple Quantum Wells on $\text{Si}(111)$ with a Y_2O_3 Buffer Layer. <i>ACS Applied Nano Materials</i> , 2018, 1, 3829-3836.	5.0	5
13	A new stable, crystalline capping material for topological insulators. <i>APL Materials</i> , 2018, 6, 066108.	5.1	7
14	High-quality thulium iron garnet films with tunable perpendicular magnetic anisotropy by off-axis sputtering correlation between magnetic properties and film strain. <i>Scientific Reports</i> , 2018, 8, 11087.	3.3	48
15	GaAs metal-oxide-semiconductor push with molecular beam epitaxy Y_2O_3 In comparison with atomic layer deposited Al_2O_3 . <i>Journal of Crystal Growth</i> , 2017, 477, 179-182.	1.5	8
16	Ultra-high thermal stability and extremely low D on $\text{HfO}_2/\text{p-GaAs}(001)$ interface. <i>Microelectronic Engineering</i> , 2017, 178, 154-157.	2.4	10
17	Enhancement of effective dielectric constant using high-temperature mixed and sub-nano-laminated atomic layer deposited $\text{Y}_2\text{O}_3/\text{Al}_2\text{O}_3$ on $\text{GaAs}(001)$. <i>Microelectronic Engineering</i> , 2017, 178, 271-274.	2.4	2
18	Relevance of $\text{GaAs}(001)$ surface electronic structure for high frequency dispersion on n-type accumulation capacitance. <i>Applied Physics Letters</i> , 2017, 110, 052107.	3.3	3

#	ARTICLE	IF	CITATIONS
19	Van der Waals epitaxy of topological insulator Bi ₂ Se ₃ on single layer transition metal dichalcogenide MoS ₂ . Applied Physics Letters, 2017, 111, .	3.3	19
20	Perfecting the Al ₂ O ₃ /In _{0.53} Ga _{0.47} As interfacial electronic structure in pushing metal-oxide-semiconductor field-effect-transistor device limits using <i>in-situ</i> atomic-layer-deposition. Applied Physics Letters, 2017, 111, .	3.3	15
21	Analysis of border and interfacial traps in ALD-Y ₂ O ₃ and -Al ₂ O ₃ on GaAs via electrical responses - A comparative study. Microelectronic Engineering, 2017, 178, 199-203.	2.4	13
22	Single-Crystal Y ₂ O ₃ Epitaxially on GaAs(001) and (111) Using Atomic Layer Deposition. Materials, 2015, 8, 7084-7093.	2.9	18
23	Single-crystal atomic layer deposited Y ₂ O ₃ on GaAs(0 0 1) " growth, structural, and electrical characterization. Microelectronic Engineering, 2015, 147, 310-313.	2.4	20
24	Synchrotron radiation photoemission study of interfacial electronic structure of HfO ₂ on In _{0.53} Ga _{0.47} As(001)-4" from atomic layer deposition. Applied Physics Letters, 2014, 104, .	3.3	11
25	Greatly improved interfacial passivation of <i>in-situ</i> high $\hat{\epsilon}$ dielectric deposition on freshly grown molecule beam epitaxy Ge epitaxial layer on Ge(100). Applied Physics Letters, 2014, 104, 202102.	3.3	13
26	Ferromagnetism in cluster free, transition metal doped high $\hat{\epsilon}$ dilute magnetic oxides: Films and nanocrystals. Journal of Applied Physics, 2013, 113, 17C309.	2.5	4
27	Detection of inverse spin Hall effect in epitaxial ferromagnetic Fe ₃ Si films with normal metals Au and Pt. Journal of Applied Physics, 2013, 113, .	2.5	23
28	Interfacial electronic structure of trimethyl-aluminum and water on an In _{0.20} Ga _{0.80} As(001)-4" surface: A high-resolution core-level photoemission study. Journal of Applied Physics, 2013, 113, .	2.5	8
29	Inversion-channel GaAs(100) metal-oxide-semiconductor field-effect-transistors using molecular beam deposited Al ₂ O ₃ as a gate dielectric on different reconstructed surfaces. Applied Physics Letters, 2013, 102, .	3.3	25
30	High-performance self-aligned inversion-channel In _{0.53} Ga _{0.47} As metal-oxide-semiconductor field-effect-transistors by <i>in-situ</i> atomic-layer-deposited HfO ₂ . Applied Physics Letters, 2013, 103, .	3.3	28
31	Growth mechanism of atomic layer deposited Al ₂ O ₃ on GaAs(001)-4" surface with trimethylaluminum and water as precursors. Applied Physics Letters, 2012, 101, 212101.	3.3	15
32	Realization of high-quality HfO ₂ on In _{0.53} Ga _{0.47} As by <i>in-situ</i> atomic-layer-deposition. Applied Physics Letters, 2012, 100, .	3.3	47
33	Effective passivation of In _{0.2} Ga _{0.8} As by HfO ₂ surpassing Al ₂ O ₃ via <i>in-situ</i> atomic layer deposition. Applied Physics Letters, 2012, 101, .	3.3	28
34	Room temperature ferromagnetic behavior in cluster free, Co doped Y ₂ O ₃ dilute magnetic oxide films. Applied Physics Letters, 2012, 101, 162403.	3.3	7
35	The influence of dislocations on optical and electrical properties of epitaxial ZnO on Si (111) using a $\hat{\epsilon}$ -Al ₂ O ₃ buffer layer. CrystEngComm, 2012, 14, 1665-1671.	2.6	12
36	Thickness-dependent lattice relaxation and the associated optical properties of ZnO epitaxial films grown on Si (111). CrystEngComm, 2012, 14, 8103.	2.6	6

#	ARTICLE	IF	CITATIONS
37	InAs MOS devices passivated with molecular beam epitaxy-grown Gd ₂ O ₃ dielectrics. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2012, 30, 02B118.	1.2	4
38	Correlation between oxygen vacancies and magnetism in Mn-doped Y ₂ O ₃ nanocrystals investigated by defect engineering techniques. Applied Physics Letters, 2012, 101, .	3.3	7
39	Atomic-scale determination of band offsets at the Gd ₂ O ₃ /GaAs (100) hetero-interface using scanning tunneling spectroscopy. Applied Physics Letters, 2011, 99, .	3.3	11
40	Thermal annealing and grain boundary effects on ferromagnetism in Y ₂ O ₃ :Co diluted magnetic oxide nanocrystals. Applied Physics Letters, 2011, 98, 031906.	3.3	10
41	The Growth of an Epitaxial ZnO Film on Si(111) with a Gd ₂ O ₃ (Ga ₂ O ₃) Buffer Layer. Crystal Growth and Design, 2011, 11, 2846-2851.	3.0	15
42	Electronic structures of Ga ₂ O ₃ (Gd ₂ O ₃) gate dielectric on Ge(001) as grown and after CF ₄ plasma treatment: A synchrotron-radiation photoemission study. Journal of Applied Physics, 2011, 109, .	2.5	3
43	Electrical properties and interfacial chemical environments of in situ atomic layer deposited Al ₂ O ₃ on freshly molecular beam epitaxy grown GaAs. Microelectronic Engineering, 2011, 88, 440-443.	2.4	29
44	MBE—Enabling technology beyond Si CMOS. Journal of Crystal Growth, 2011, 323, 511-517.	1.5	6
45	Magnetization reversal processes of epitaxial Fe ₃ Si films on GaAs(001). Journal of Applied Physics, 2011, 109, 07D508.	2.5	5
46	Attainment of low interfacial trap density absent of a large midgap peak in In _{0.2} Ga _{0.8} As by Ga ₂ O ₃ (Gd ₂ O ₃) passivation. Applied Physics Letters, 2011, 98, 062108.	3.3	23
47	High-resolution core-level photoemission study of CF ₄ -treated Gd ₂ O ₃ (Ga ₂ O ₃) gate dielectric on Ge probed by synchrotron radiation. Applied Physics Letters, 2011, 98, .	3.3	10
48	Low interfacial trap density and sub-nm equivalent oxide thickness in In _{0.53} Ga _{0.47} As (001) metal-oxide-semiconductor devices using molecular beam deposited HfO ₂ /Al ₂ O ₃ as gate dielectrics. Applied Physics Letters, 2011, 99, .	3.3	53
49	InGaAs and Ge MOSFETs with a common high- κ gate dielectric. , 2010, , .		0
50	Effective reduction of interfacial traps in Al ₂ O ₃ /GaAs (001) gate stacks using surface engineering and thermal annealing. Applied Physics Letters, 2010, 97, 112901.	3.3	66
51	Energy-band parameters of atomic layer deposited Al ₂ O ₃ and HfO ₂ on In _x Ga _{1-x} As. Applied Physics Letters, 2009, 94, .	3.3	66
52	Ga ₂ O ₃ (Gd ₂ O ₃) on Ge without interfacial layers: Energy-band parameters and metal oxide semiconductor devices. Applied Physics Letters, 2009, 94, 202108.	3.3	30
53	InGaAs Metal Oxide Semiconductor Devices with Ga ₂ O ₃ (Gd ₂ O ₃) High- κ Dielectrics for Science and Technology beyond Si CMOS. MRS Bulletin, 2009, 34, 514-521.	3.5	35
54	Research advances on III-V MOSFET electronics beyond Si CMOS. Journal of Crystal Growth, 2009, 311, 1944-1949.	1.5	11

#	ARTICLE	IF	CITATIONS
55	Nano-electronics of high κ dielectrics on InGaAs for key technologies beyond Si CMOS. , 2009, , .		2
56	Inversion-channel GaN MOSFET using atomic-layer-deposited Al₂O₃ as gate dielectric. , 2009, , .		1
57	High performance Ga₂O₃(Gd₂O₃)/Ge MOS devices without interfacial layers. , 2009, , .		0
58	Self-aligned inversion-channel In_{0.75}Ga_{0.25}As MOSFETs using MBE-Al₂O₃/Ga₂O₃(Gd₂O₃) and ALD-Al₂O₃ as gate dielectrics. , 2009, , .		0
59	Transmission electron microscopy characterization of HfO₂/GaAs(001) heterostructures grown by molecular beam epitaxy. Applied Physics A: Materials Science and Processing, 2008, 91, 585-589.	2.3	9
60	High-performance self-aligned inversion-channel In_{0.53}Ga_{0.47}As metal-oxide-semiconductor field-effect-transistor with Al₂O₃(Gd₂O₃) as gate dielectrics. Applied Physics Letters, 2008, 93, .	3.3	120
61	Atomic-layer-deposited HfO₂ on In_{0.53}Ga_{0.47}As: Passivation and energy-band parameters. Applied Physics Letters, 2008, 92, .	3.3	109
62	Achieving a low interfacial density of states in atomic layer deposited Al₂O₃ on In_{0.53}Ga_{0.47}As. Applied Physics Letters, 2008, 93, 202903.	3.3	60
63	Sub-nanometer EOT scaling on In_{0.53}Ga_{0.47}As with atomic layer deposited HfO₂ as gate dielectric. International Power Modulator Symposium and High-Voltage Workshop, 2008, , .	0.0	0
64	Oxide scalability in Al₂O₃-Ga₂O₃(Gd₂O₃)-In_{0.20}Ga_{0.80}As heterostructures. Journal of Vacuum Science & Technology B, 2008, 26, 1132.	1.3	10
65	Inversion n-channel GaN MOSFETs with atomic-layer-deposited Al₂O₃ as gate dielectrics. , 2008, , .		0
66	Self-aligned inversion-channel and D-mode InGaAs MOSFET using		

#	ARTICLE	IF	CITATIONS
73	Structural and compositional investigation of yttrium-doped HfO ₂ films epitaxially grown on Si (111). Applied Physics Letters, 2007, 91, 202909.	3.3	17
74	Interfacial self-cleaning in atomic layer deposition of HfO ₂ gate dielectric on In _{0.15} Ga _{0.85} As. Applied Physics Letters, 2006, 89, 242911.	3.3	117
75	Molecular beam epitaxy grown template for subsequent atomic layer deposition of high ϵ dielectrics. Applied Physics Letters, 2006, 89, 222906.	3.3	17
76	Structure of HfO ₂ films epitaxially grown on GaAs (001). Applied Physics Letters, 2006, 89, 122907.	3.3	24
77	MBE-grown high gate dielectrics of HfO ₂ and (Hf ϵ -Al)O ₂ for Si and III ϵ -V semiconductors nano-electronics. Journal of Crystal Growth, 2005, 278, 619-623.	1.5	26
78	Thermodynamic stability of Ga ₂ O ₃ (Gd ₂ O ₃) ϵ -GaAs interface. Applied Physics Letters, 2005, 86, 191905.	3.3	56
79	Surface passivation of III-V compound semiconductors using atomic-layer-deposition-grown Al ₂ O ₃ . Applied Physics Letters, 2005, 87, 252104.	3.3	371
80	Epitaxial Growth and Structure of Thin Single Crystal ϵ -Al ₂ O ₃ Films on Si (111) Using e-Beam Evaporation of Sapphire in Ultra-High Vacuum. Materials Research Society Symposia Proceedings, 2004, 811, 369.	0.1	2
81	Structure of Sc ₂ O ₃ Films Epitaxially Grown on ϵ -Al ₂ O ₃ (111). Materials Research Society Symposia Proceedings, 2004, 811, 49.	0.1	3
82	GaAs MOSFET with oxide gate dielectric grown by atomic layer deposition. IEEE Electron Device Letters, 2003, 24, 209-211.	3.9	223
83	Advances in GaAs Mosfet's Using Ga ₂ O ₃ (Gd ₂ O ₃) as Gate Oxide. Materials Research Society Symposia Proceedings, 1999, 573, 219.	0.1	49
84	Ga ₂ O ₃ (Gd ₂ O ₃)/InGaAs enhancement-mode n-channel MOSFETs. IEEE Electron Device Letters, 1998, 19, 309-311.	3.9	135
85	Effect of temperature on Ga ₂ O ₃ (Gd ₂ O ₃)/GaN metal ϵ -oxide ϵ -semiconductor field-effect transistors. Applied Physics Letters, 1998, 73, 3893-3895.	3.3	217
86	Demonstration of enhancement-mode p- and n-channel GaAs MOSFETS with Ga ₂ O ₃ (Gd ₂ O ₃) As gate oxide. Solid-State Electronics, 1997, 41, 1751-1753.	1.4	151
87	Recombination velocity at oxide ϵ -GaAs interfaces fabricated by in situ molecular beam epitaxy. Applied Physics Letters, 1996, 68, 3605-3607.	3.3	71